

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Group Art Unit: 1112

Examiner: To Be Assigned

In Re PATENT APPLICATION Of:

Applicant(s) : LIU et al.

Serial No. : 08/958,460

Filed : October 28, 1997

For : HIGH DENSITY PLASMA
CHEMICAL VAPOR DEPOSITION
PROCESS

Attorney Ref.: JIA 462

STATUS REQUEST


Assistant Commissioner for Patents
Washington, DC 20231

Sir:

Please let us know the status of the above-identified application and when an
Action may be expected.

Respectfully submitted,

Date: 8/2/1999


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SMR/bec

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TC 1700 MAIL ROOM

acted on 8/19/99.


RABON SERGENT
PRIMARY EXAMINER

FEE ENCLOSED \$0
Please charge any further
fee to our Deposit Account
No. 18-0002

#1/State
Report
8/31/99
O'Brien
AUG 02 1999
PATENT & TRADEMARK OFFICE